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Fourteenth International Conference on Quality Control by Artificial Vision

**Christophe Cudel
Stéphane Bazeille
Nicolas Verrier**
Editors

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Introduction

Researchers from Université Haute Alsace and the IRIMAS Research Institute were proud to host the Fourteenth International Conference on Quality Control by Artificial Vision (QCAV 2019) in Mulhouse, France, 15–17 May. This international conference was first organized in France in 1993 and has occurred biannually since then with host sites worldwide including: Le Creusot, France in 1995, 1997, 2001, 2007, and 2015; Japan in 1998, 2005, 2013, and 2017; Canada in 1999; the United States in 2003; Austria 2009, and Saint Étienne, France in 2011.

Quality Control by Artificial Vision continues to undergo rapid evolution thanks to recent progress in the fields of artificial intelligence, 2D and 3D vision sensors, image processing, and non-conventional optics. This year, the main topics were 2D and 3D machine vision, machine learning, and artificial intelligence (AI). The conference was also honored with the presence of two renowned guest speakers: Prof. Pascal Picart, Université du Mans (France) and Dr. Yvo Ehrke, Carl Zeiss GmbH (Germany), who delivered talks exploring non-conventional imaging systems and light field imaging.

For the fourteenth QCAV conference proceedings, fifty papers were selected by the International Committee from among seventy-eight submissions (five of which were presented in the conference's poster session). The authors were from Austria, Australia, Qatar, France, Japan, Pakistan, United Kingdom, Spain, Columbia, Germany, Greece, India, Luxembourg, Morocco, Peru, Belgium, Sri Lanka, Saudi Arabia, Mexico, and Italy.

It is also our pleasure to announce a special issue of the Journal of Electronic Imaging published by SPIE, with guest editors Prof. Olivier Aubreton, Université de Bourgogne (France), Prof. Kunihiro Kato, Gifu University (Japan), and Prof. Christophe Cudel, Université Haute-Alsace (France), dedicated to QCAV and featuring selections based on the best papers presented at the conference, among other submissions.

We also would like to thank our partners and sponsors for their support: La Faculté des Sciences de Mulhouse (France); Mulhouse Alsace Agglomération (France); and La Région Grand-Est; IDS GmbH (Germany).

**Christophe Cudel
Stéphane Bazeille
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